

PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1
 Stylesheet Version v1.2

EPAS ID: PAT4582194

SUBMISSION TYPE:	RESUBMISSION	
NATURE OF CONVEYANCE:	CHANGE OF NAME	
RESUBMIT DOCUMENT ID:	504440601	
CONVEYING PARTY DATA		
Name		Execution Date
SHANGHAI MICRO ELECTRONICS EQUIPMENT CO., LTD.		01/20/2017
RECEIVING PARTY DATA		
Name:	SHANGHAI MICRO ELECTRONICS EQUIPMENT (GROUP) CO., LTD.	
Street Address:	1525 ZHANGDONG ROAD, ZHANGJIANG HIGH-TECH PARK	
City:	SHANGHAI	
State/Country:	CHINA	
Postal Code:	201203	
PROPERTY NUMBERS Total: 30		
Property Type	Number	
Application Number:	13991080	
Application Number:	13976353	
Application Number:	13976376	
Application Number:	14002561	
Application Number:	14002917	
Application Number:	14115284	
Application Number:	14239515	
Application Number:	14385464	
Application Number:	14408130	
Application Number:	14343079	
Application Number:	14437775	
Application Number:	14655465	
Application Number:	14758720	
Application Number:	14900073	
Application Number:	14910994	
Application Number:	15109040	
Application Number:	15038992	
Application Number:	15108663	
Application Number:	15108083	

PATENT

Property Type	Number
Application Number:	15108886
Application Number:	15122019
Application Number:	15323544
Application Number:	15515110
Application Number:	15523140
Application Number:	15403581
Application Number:	12304189
Application Number:	12295108
Application Number:	12302824
Application Number:	12299077
Application Number:	12444631

CORRESPONDENCE DATA

Fax Number: (703)621-7155

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

Phone: 7036217140

Email: mailroom@mg-ip.com, cds@mg-ip.com

Correspondent Name: MUNCY, GEISSLER, OLDS & LOWE, PC

Address Line 1: 4000 LEGATO RD., SUITE 310

Address Line 4: FAIRFAX, VIRGINIA 22033

ATTORNEY DOCKET NUMBER:	0118/0239M
NAME OF SUBMITTER:	JOE MCKINNEY MUNCY
SIGNATURE:	/Joe McKinney Muncy/
DATE SIGNED:	09/06/2017

Total Attachments: 4

source=2017-09-06 Corrective Assignment documents#page4.tif

source=2017-09-06 Corrective Assignment documents#page5.tif

source=2017-09-06 Corrective Assignment documents#page6.tif

source=2017-09-06 Corrective Assignment documents#page7.tif

VERIFICATION OF TRANSLATION

The undersigned hereby declares the following:

That I am knowledgeable in Chinese and English. That I have reviewed the Notification of the Recordal of a Change and verify that the attached document is an accurate translation thereof.

All statements made herein of my own knowledge are true and all statements made on information and belief are believed to be true. Further, these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

18 August 2017
Date

Jing Zhong
Signature

Jing Zhong
Typed or Printed Name

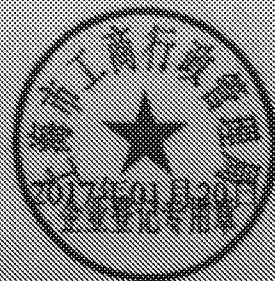
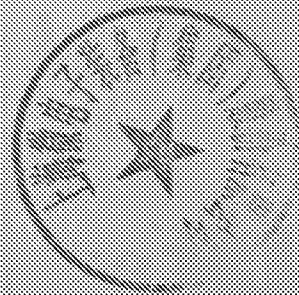
准予变更登记通知书

NO. 000000012017011800005
统一社会信用代码:
91310000326604790J

上海微电子装备（集团）股份有限公司：

经审查，你提交的上海微电子装备（集团）股份有限公司迁入登记（原企业名称上海微电子装备有限公司，变更后企业名称上海微电子装备（集团）股份有限公司）申请材料齐全，符合法定形式，我局决定准予变更登记。请自本通知书发出之日起第10个工作日到我局换领营业执照。

注册官：



注 本文书一式二份，一份送达申请人，一份登记机关留存。
此份送达申请人。

Notification Approving the Recordal of Change

No. 00000001201701180006

Registration No. 91310000736664790J

SHANGHAI MICRO ELECTRONICS EQUIPMENT (GROUP) CO., LTD.:

Your application for the recordal of changes of Name (company name before change: SHANGHAI MICRO ELECTRONICS EQUIPMENT CO., LTD.; company name after change: SHANGHAI MICRO ELECTRONICS EQUIPMENT (GROUP) CO., LTD.) has been received. After careful review and examination, our office confirms that the application materials are complete and comply with the formal requirements. Our office herewith approves the recordal of the changes and will issue a new business license to your company within 10 working days.

Officer: (Signature)

Shanghai Administrative Bureau for Industry and Commerce

(Stamp)

January 20, 2017

No.	Current Status	Savvy Ref.	MG-IP Ref.	Title of Invention	PCT Appl. No.	Priority No.	US Appl. No.	Date of Patent	Patent No.
1	Granted	PCT111671US	0118/0112PUS1	PROJECTION OBJECTIVE LENS SYSTEM	PCT/CN2011/082945	201010567535.9	13/991,080	3/3/2015	8970964
2	Pending	PCT111699US	0118/0115PUS1	LARGE FIELD PROJECTION OBJECTIVE FOR LITHOGRAPHY	PCT/CN2011/083616	201010619283.X	13/976,353		
3	Granted	PCT111794US	0118/0116PUS1	BACKSIDE ALIGNMENT APPARATUS AND METHOD	PCT/CN2011/084264	201010619055.2	13/976,376	11/17/2015	9,188,434
4	Granted	PCT120291US	0118/0121PUS1	SPLIT TYPE AEROSTATIC BEARING	PCT/CN2012/071057	201110053278.1	14/002,561	12/30/2014	8920031
5	Granted	PCT120314US	0118/0124PUS1	METHOD FOR MEASURING DISTORTION OF PROJECTION OBJECTIVE	PCT/CN2012/072693	201110068060.3	14/002,917	2/9/2016	9256138
6	Granted	PCT120686US	0118/0134PUS1	METHOD FOR MEASURING AND CALIBRATING CENTROID OF COARSE STAGE OF PHOTOLITHOGRAPHY TOOL	PCT/CN2012/074910	201110113563.8	14/115,284	12/13/2016	9,519,231
7	Granted	PCT120689US	0118/0149PUS1	INTERFERENCE EXPOSURE DEVICE AND METHOD	PCT/CN2012/080258	201110241758.0	14/239,515	11/24/2015	9195146
8	Granted	PCT130363US	0118/0157PUS1	LASER ANNEALING APPARATUS AND LASER ANNEALING METHOD	PCT/CN2013/079697	201210258008.9	14/385,464	9/27/2016	9,455,164
9	Pending	PCT130367US	0118/0160PUS1	LINEAR MOTOR AND STAGE APPARATUS	PCT/CN2013/078671	201210270584.5; 201210525941.8	14/408,130		
10	Granted	PCT131303US	0118/0169PUS1	OFF-AXIS ALIGNMENT SYSTEM AND ALIGNMENT METHOD	PCT/CN2013/080800	201210402248.1	14/434,079	9/20/2016	9,448,488
11	Granted	PCT131305US	0118.0171PUS1	BALANCE MASS SYSTEM SHARED BY WORKPIECE TABLE AND MASK TABLE, AND LITHOGRAPHY MACHINE	PCT/CN2013/084005	201210451784.0	14/437,775	3/7/2017	9588444
12	Pending	PCT131309US	0118/0182PUS1	WARPED SILICON-CHIP ADSORPTION DEVICE AND ADSORPTION METHOD THEREOF	PCT/CN2013/090565	201210586817.2	14/655,465		
13	Pending	PCT131311US	0118/0180PUS1	MAGNETIC ALIGNMENT SYSTEM AND ALIGNMENT METHOD THEREFOR	PCT/CN2014/071089	201310030302.9	14/758,720		
14	Pending	PCT133204US	0118/0193PUS1	RETICLE SHAPE REGULATION DEVICE AND METHOD, AND EXPOSURE APPARATUS USING SAME	PCT/CN2014/079602	201310245138.3	14/900,073		
15	Pending	PCT133206US	0118/0202PUS1	HALBACH ARRAY AND MAGNETIC SUSPENSION DAMPER USING SAME	PCT/CN2014/083777	201310347667.4	14/910,994		
16	Pending	PCT141090US	0118/0216PUS1	Silicon Wafer Pre-alignment Device and Method Therefor	PCT/CN2014/095105	201310752191.2; 201410367501.3	15/109,040		
17	Pending	PCT141094US	0118/0212PUS1	Flat Voice Coil Motor	PCT/CN2014/090589	201310612815.0	15/038,992		
18	Pending	PCT141098US	0118/0217PUS1	Reticle Shape Correction Apparatus and Photolithography Tool Using Same	PCT/CN2014/092425	201310752194.6	15/108,663		
19	Pending	PCT142591US	0118.0214PUS1	Silicon Wafer Edge Protection Device with Collision Protection Function	PCT/CN2014/095044	201310734687.7	15/108,083		
20	Pending	PCT142593US	0118/0215PUS1	FOCUSING LEVELING DEVICE	PCT/CN2014/094771	201310747393.8	15/108,886		
21	Pending	PCT142595US	0118.0220PUS1	Lithography Machine Workpiece Table and Vertical Position Initialization Method Thereof	PCT/CN2015/072835	201410070238.1	15/122,019		
22	Pending	PCT150181US	0118/0226PUS1	Laser Annealing Device	PCT/CN2015/083250	201410243344.5	15/323,544		
23	Pending	PCT150191US	0118/0232PUS1	EXPOSURE DEVICE AND OUT-OF-FOCUS AND TILT ERROR COMPENSATION METHOD	PCT/CN2015/083842	201410508363.6	15/515,110		
24	Pending	PCT150193US	0118/0234PUS1	ADJUSTING DEVICE AND ADJUSTING METHOD FOR EXPOSURE DEVICE	PCT/CN2015/092900	201410597382.0	15/523,140		
25	Pending	US163621	0118.0227PUS1	Apparatus and Method for 3D Surface Inspection	N/A	N/A	15/403,581		
26	Granted	PCT06062US	N/A	Immersion flow field maintenance system for an immersion lithography machine	PCT/CN2006/003592	200610027707.7	12/304,189	3/6/2012	8130365
27	Granted	PCT06063US	N/A	Method for in-situ aberration measurement of optical imaging system in lithographic tools	PCT/CN2006/003591	200610025445.0	12/295,108	10/11/2011	8035801
28	Granted	PCT06064US	N/A	Large-field unit-magnification projection optical system	PCT/CN2006/003271	200610027264.1	12/302,824	6/29/2010	7746571
29	Granted	PCT06066US	N/A	Precise positioning system for dual stage switching exposure	PCT/CN2006/003126	200620044000.2	12/299,077	9/27/2011	8027028
30	Granted	PCT06067US	N/A	Dual stage positioning and switching system	PCT/CN2006/003270	200610116453.6	12/444,631	3/13/2012	8134689